

FORM PTO 1449 (modified)			ATTY DOCKET NO. 03500.017731.	APPLICATION NO. 10/533,091			
U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE			APPLICANT HIDEYA KUMOMI, ET AL.				
LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary)			FILING DATE April 28, 2005	GROUP 2812			
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
AR		5,130,103	07/14/92	Yamagata et al.	428	209	—
		5,207,863	05/04/93	Kumomi	156	603	—
		5,290,712	03/01/94	Sato, et al.	437	24	—
AR		5,723,348	03/03/98	Kumomi et al.	437	23	—
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR/ABSTRACT
AR	JP	8-8197	01/12/96	Japan	—	—	Abstract
							—
							—
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OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)							
AR		Kumomi, et al. "Selective Nucleation-based Epitaxy (SENTAXY): A novel Approach for Thin Film Formation"; JPN J. Appl. Phys., Vol. 36 pp 1383-1388 (1997).					
		Kumomi, et al. "Fundamentals for the Formation and Structure Control of Thin Films: Nucleation, Growth, Solid-state Transformations"; Handbook of Thin Film Materials, Vol. 7, Ch. 6, pp 319-373 (2002).					
		Hatano, et al. "Excimer Laser-induced Temperature Field in Melting and Resolidification of Silicon Thin Films"; J. Appl. Phys., Vol. 87, No. 1, pp. 36-43 (2000).					
AR		Van der Wilt, et al. "Formation of Location-controlled Crystalline Islands Using Substrate-embedded Seeds in Excimer-laser Crystallization of Silicon Films"; Appl. Phys. Lett, Vol. 79, No. 12, pp 1819-1821 (2001)					
EXAMINER	AR		DATE CONSIDERED	09/20/07			

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Sheet 1 of 1

FORM PTO 1449 (modified) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary)			ATTY DOCKET NO. <b>03500.017731</b>	APPLICATION NO.: National Stage of PCT/EP040507 <b>107533091</b>			
			APPLICANT: <b>HIDEYA KUMOMI</b>				
			FILING DATE <b>April 28, 2005</b> Herewith	GROUP <b>NYA 2812</b>			
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*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
<i>AR</i>		4,564,403	1/1986	Hayafuji et al.	148	171	_____
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		5,021,119	6/1991	Fan et al.	_____	_____	_____
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		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT
<i>AR</i>	GB	2338342	12/199	United Kingdom	_____	_____	Corresp to USP 6,326,286
	EP	0472970	3/1992	Europe	_____	_____	Corresp to USP 5,318,661
	EP	1262578	12/2002	Europe	_____	_____	Corresp. to 2003/003766
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<i>AR</i>		Kuriyama et al., "Comprehensive Study ... Thin Film Transistors", Jpn. J. Appl. Phys., Vol. 33, (Part 1, No. 10) (1994) 5657-5662.					
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		Patent Abstracts of Japan, Vol. 0080, No. 52 (C-213) 3-1984 for JP 58-208297					
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EXAMINER <i>AR</i>		DATE CONSIDERED <i>09/20/05</i>					

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